IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Attorney Docket No. 249/255 DIV

In re patent application of

Im-soo PARK, et al.

Serial No.

[Division of Serial No. 09/899,226, filed July 6, 2001]

Filed: October 16, 2003

For: APPARATUS FOR CLEANING SEMICONDUCTOR WAFER AND METHOD FOR CLEANING WAFER USING THE SAME

CONFIRMATION
CLAIM FOR CONVENTION PRIORITY

Commissioner for Patents
Alexandria, VA 22313-1450

Sir:

The benefit of the filing date of the following prior foreign application filed in the following foreign country is hereby requested, and the right of priority provided in 35 U.S.C. §119 is hereby claimed:

Application No. 01-2065 - filed 13 January 2001 - Republic of Korea

In support of this claim, a certified copy of said original foreign application was filed in parent application Serial No. 09/899,226 on July 6, 2001.

Acknowledgment of applicant's claim for priority and receipt of the certified priority document is solicited.

Respectfully submitted,

Date: October 16, 2003

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